

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A maintenance system of a substrate processing apparatus, comprising:

a remote operation unit for operating said substrate processing apparatus from a remote place by transmitting a remote operation information to a side of said substrate processing apparatus through a communication network and providing said remote operation information to said substrate processing apparatus; and

a communication control unit for receiving said remote operation information transmitted to the side of said substrate processing apparatus and providing said remote operation information to said substrate processing apparatus,

wherein said communication control unit provides said remote operation information to said substrate processing apparatus only when there is an allow setting for a remote operation by a worker in the side of said substrate processing apparatus,

the allow setting of the remote operation is divided into plural stages,

an allow setting of the remote operation accompanying a driving of said substrate processing apparatus and an allow setting of the remote operation not accompanying the driving of said substrate processing apparatus are included in separate stages,

the remote operation accompanying the driving of said substrate processing apparatus includes

a position adjustment for a substrate carrier arm, a resist solution discharge nozzle in a resist coating unit and a developing solution discharge nozzle in a developing unit in said substrate processing apparatus, and

a movement confirmation of the substrate carrier arm, the resist solution discharge nozzle and the developing solution discharge nozzle, and

the remote operation not accompanying the driving of said substrate processing apparatus includes

a setting change for a discharge amount of the resist solution, a discharge pressure of the resist solution, a turning speed of a substrate, an atmospheric temperature and an atmospheric humidity in the resist coating unit,

a setting change for a discharge amount of the developing solution, a discharge pressure of the developing solution, an atmospheric temperature and an atmospheric humidity in the developing unit, and

a setting change for a heating temperature and a heating time of the substrate in a heating unit.

Claim 2 (Original): The maintenance system as set forth in claim 1,  
wherein said communication control unit comprises an allow-setting section for performing the allow setting of the remote operation and said allow-setting section is provided only to the side of said substrate processing apparatus of said communication network.

Claim 3 (Canceled).

Claim 4 (Original): The maintenance system as set forth in claim 1, further comprising:

a sensor for detecting an approach of a person to said substrate processing apparatus in the side of said substrate processing apparatus.

Claim 5 (Original): The maintenance system as set forth in claim 1,

wherein an information communication performed through said communication network is enabled only when there is an allow setting for a communication.

Claim 6 (Canceled).

Claim 7 (Currently Amended): The maintenance system as set forth in claim ~~[[6]]~~ 1, wherein the remote operation accompanying the driving of said substrate processing apparatus is a remote operation accompanying a physical movement with respect to various types of elements including a substrate carrier member in said substrate processing apparatus, and

wherein the remote operation not accompanying the driving of said substrate processing apparatus is a remote operation not accompanying the physical movement with respect to the various types of elements.

Claim 8 (Canceled).

Claim 9 (Original): The maintenance system as set forth in claim 4, wherein an operation for starting a detection by said sensor can be performed in the side of said substrate processing apparatus or in the side of said remote operation unit with said communication network put therebetween; and

wherein an operation for stopping the detection by said sensor can be performed only in the side of said substrate processing apparatus.

Claim 10 (Original): The maintenance system as set forth in claim 4,

wherein said sensor can selectively detect the approach of the person other than workers identified in advance.

Claims 11-20 (Canceled).

Claim 21 (Currently Amended): A remote operation unit,  
capable of remotely operating a substrate processing apparatus by transmitting a remote operation information to a side of said substrate processing apparatus through a communication network and providing the remote operation information to said substrate processing apparatus[[:]] and,

wherein the remote operation information transmitted to the side of said substrate processing apparatus is provided only when there is an allow setting for the remote operation by a worker in the side of said substrate processing apparatus,

an information communication performed through said communication network is enabled only when there is an allow setting for a communication,

an allow setting of the remote operation accompanying a driving for said substrate processing apparatus and an allow setting of the remote operation not accompanying the driving for said substrate processing apparatus are included in separate stages,

the remote operation accompanying the driving of said substrate processing apparatus includes

a position adjustment for a substrate carrier arm, a resist solution discharge nozzle in a resist coating unit and a developing solution discharge nozzle in a developing unit in said substrate processing apparatus, and

a movement confirmation of the substrate carrier arm, the resist solution discharge nozzle and the developing solution discharge nozzle, and

the remote operation not accompanying the driving of said substrate processing apparatus includes

a setting change for a discharge amount of the resist solution, a discharge pressure of the resist solution, a turning speed of a substrate, an atmospheric temperature and an atmospheric humidity in the resist coating unit,

a setting change for a discharge amount of the developing solution, a discharge pressure of the developing solution, an atmospheric temperature and an atmospheric humidity in the developing unit, and

a setting change for a heating temperature and a heating time of the substrate in a heating unit.

Claim 22 (Original): The remote operation unit as set forth in claim 21, further comprising:

an allow-setting section for performing the allow setting of the remote operation is provided only in the side of said substrate processing apparatus of said communication network.

Claim 23 (Original): The remote operation unit as set forth in claim 21, wherein the allow setting of the remote operation is divided into plural stages.

Claim 24 (Original): The remote operation unit as set forth in claim 21, further comprising:

a sensor for detecting an approach of a person to said substrate processing apparatus in the side of said substrate processing apparatus.

Claims 25-26 (Canceled).

Claim 27 (Currently Amended): The remote operation unit as set forth in claim [[26]]  
21,

wherein the remote operation accompanying the driving of said substrate processing apparatus is a remote operation accompanying a physical movement with respect to various types of elements including a substrate carrier member in said substrate processing apparatus, and

wherein the remote operation not accompanying the driving of said substrate processing apparatus is a remote operation not accompanying the physical movement with respect to the various types of elements.

Claim 28 (Canceled).

Claim 29 (Original): The remote operation unit as set forth in claim 24,

wherein an operation for starting a detection by said sensor can be performed in the side of said substrate processing apparatus or in the side of said remote operation unit with said communication network put therebetween; and

wherein an operation for stopping the detection by said sensor can be performed only in the side of said substrate processing apparatus.

Claim 30 (Original): The remote operation unit as set forth in claim 24,

wherein said sensor can selectively detect the approach of the person other than workers identified in advance.

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Claim 31 (Canceled).